

Inventor: John F. Van Itallie et al.

Title: Photolithographic Methods of Using a Single Reticle to Form Overlapping  
Patterns

Assignee: Micron Technology, Inc.

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application, except for U. S. Patent Application Serial No. US2003/0152844A1. The above-identified application is a continuation application of co-pending application Serial No. 09/943,186, filed August 29, 2001. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned, except for U. S. Patent Application Serial No. US2003/0152844A1. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated:

12/5/03

By:



David G. Latwesen, Ph.D.  
Reg. No. 38,533

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
MI22-2458SERIAL NO. PRIORITY  
09/943,186LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
John F. Van ItallieFILING DATE PRIORITY  
August 29, 2001GROUP  
Unknown

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,248,508 B1	06-2001	Murooka et al.			
	AB	US2003/015284A1	08-2003	Dulman			Feb. 5, 2002
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AQ							
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		

EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.